

ABSTRACT OF THE DISCLOSURE

An exposure apparatus for exposing a substrate using a plurality of masters. The apparatus includes a stage being able to install at least one of the plurality of masters, a first housing surrounding said stage, a second housing for stocking at least one of the plurality of masters, the second housing being installed adjacent to the first housing or installed in an interior of the first housing, the second housing being allowed to communicate with the first housing, and a third housing being installed between an inside space and an outside space of the first housing, the third housing being different from said first and second housings. The first and second housings are filled by an inert gas or are adapted to be evacuated.